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FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO IMEC222 001AUS	APPLICATION NO. 09/955,565
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)		APPLICANT Hantschel, et al.	GROUP 2878
		FILING DATE September 12, 2001	

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)

FOREIGN PATENT DOCUMENTS								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
TXC		EP 0 763 844 B1	06/07/00	EUROPE			X	

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)
TXC	Hantschel, T., et al., "The fabrication of a full metal AFM probe and its applications for Si and InP device analysis", Proc. Micromachining and Microfabrication Conference, (1999).
TXC	Hantschel, T., et al., "Fabrication and use of metal tip and tip-on-tip probes for AFM-based device analysis", Proc. of SPIE, 3512, pp. 92-103, (1998)
TXC	Hantschel, T., et al., "The peel-off probe: a cost-effective probe for electrical atomic force microscopy", Proc. SPIE, vol. 4175, pp. 50-59, (September 18-19, 2000)
	Rasmussen, J., et al., "Fabrication of an all-metal atomic force microscope probe", Proc. of Transducers 1997, pp. 463-466, (1997)

EXAMINER	DATE CONSIDERED
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*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.